

RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 1792
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q84452

Michel PUECH

Appln. No.: 10/516,455

Group Art Unit: 1792

Confirmation No.: 2876

Examiner: Allan W. OLSEN

Filed: December 3, 2004

For: METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER
INDUCTIVELY COUPLED PLASMA

RESPONSE UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 5, 2008, please consider the remarks as found
on the accompanying pages.

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